

Title (en)
Piezoelectric device and manufacturing method thereof

Title (de)
Piezoelektrische Anordnung und ihr Herstellungsverfahren

Title (fr)
Dispositif piézoélectrique et sa méthode de fabrication

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Application
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Abstract (en)
The invention is directed to piezoelectric device having a vibration space that achieves a high degree of airtightness which is not readily reduced, and a manufacturing method thereof. First and second hollow layers (21) and (31) are formed at first and second surfaces of a piezoelectric substrate (11) to form first and second cavities (6) and (7) around first and second electrodes (12) and (13) respectively. The first and second cavities (6) and (7) each have a uniform width and extend between a first surface and an opposing second surface of the first and second hollow layers (21) and (31) respectively, around vibration portions of the piezoelectric element (1). First and second sealing layers (22) and (32) are each formed on the second surface of the first and second hollow layers (21) and (31) to seal the first and second cavities (6) and (7). <IMAGE>

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IPC 8 full level
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